AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

LISTING OF CLAIMS:

1. (currently amended) Apparatus (1) for treating wafer-shaped articles, comprising:

~~1.1a~~ a linear arranged process unit array ~~of a plurality~~ of at least two process units (31, 33), wherein in each ~~such~~ said process unit only and exactly one single wafer-shaped article (Wm) can be treated at one time;

~~1.2a~~ at least one cassette-holding unit (15), each cassette-holding unit for holding at least one cassette storing at least one wafer-shaped article therein;

~~1.3a~~ a transport system for picking a held wafer-shaped article from [[a]] the one cassette and placing ~~it~~ the thus picked-up wafer-shaped article into one of [[a]] the process ~~unit 1.4~~ units, the transport system comprising[[:]]

~~1.4.1~~ i) at least one linear track (26) arranged parallel to the process unit array ~~of the plurality of process units~~ (31, 33), the track for moving ~~at least one~~ the picked-up single wafer-shaped article along a linear path parallel to the process unit array ~~of the plurality of process units~~, and

~~1.4.2~~ ii) a transport unit (46) movably mounted on each of said at least one linear track (26),[[;]] said transport unit

comprising at least one holding means (46a) for holding ~~a single~~ the picked-up wafer-shaped article in a substantially vertical plane parallel to the linear track and moving the picked-up wafer-shaped article along a transport path defined by the linear track, wherein the transport unit (46) has a pivoting (66) mechanism for pivoting (P) the picked-up wafer-shaped article from a substantially vertical state to a substantially horizontal state to place the picked-up wafer-shaped article in one of the process units.

2. (cancelled)

3. (currently amended) Apparatus as claimed in claim 1, further comprising:

a front unit ~~wherein~~ comprising

i) an array of at least two of the cassette-holding units (15) for holding cassettes storing a plurality of the wafer-shaped articles ~~is arranged~~ and

ii) a transfer unit (84, 86) for transferring the wafer-shaped ~~article~~ articles between the ~~cassette~~ cassettes and the transport unit (46) ~~of the at least one linear track (26)~~.

4. (currently amended) Apparatus as claimed in claim [[1]] 3, further comprising:

at least one transfer station (22) for temporarily storing the picked-up wafer-shaped article (Wt),

the transfer station being accessible by the transfer unit (84, 86) and by the transport unit (46) movably mounted on the linear track.

5. (currently amended) Apparatus as claimed in claim 4, wherein said transfer station (22) comprises a flip mechanism for flipping (Fv) the picked-up wafer-shaped article.

6. (currently amended) Apparatus as claimed in claim 4, wherein said transfer station ~~comprising~~ further comprises a holding unit (42) with two holding devices (42a, 42b) arranged in a back-to-back configuration.

7. (currently amended) Apparatus as claimed in claim 1, wherein said transport unit (46) comprises a flip mechanism for flipping the picked-up wafer-shaped article and two holding devices (46a, 46b).

8. (currently amended) Apparatus as claimed in claim 7, wherein the two holding devices (46a, 46b) are arranged in a back-to-back configuration.

9. (currently amended) Apparatus as claimed in claim 1, with a transport system comprising at least two of said at least one linear tracks (24, 26).

10. (new) Apparatus as claimed in claim 1, wherein,

each process units (31, 33) treats the only exactly one single wafer-shaped article (Wm) in a horizontal position, and

a transport path of the held wafer is narrower than a diameter of the held wafer.

11. (new) Apparatus (1) for treating wafer-shaped articles comprising:

a linear first process unit array located opposite a linear second process unit array, each of the first and second processing unit arrays comprising plural process units (31, 33, 35, 37) for treating wafers in a horizontal position, each said process unit configured to treat exactly and only one single wafer (Wm) at a time;

a cassette-holding unit located at one end of the first and second process unit arrays, the cassette-holding unit for horizontally holding a cassette horizontally storing at least one wafer therein; and

a transport system comprising a track (24, 26) located between the first and second process unit arrays, the transport system configured for picking the one wafer from the cassette,

changing the one wafer from a horizontal position to a vertical position, moving the vertically-positioned wafer along the track and adjacent to one of the process units, and changing the vertically-positioned wafer to the horizontal position to place the wafer into the one process unit for treating.

12. (new) The apparatus of claim 11, wherein,

the transport system further comprises a transport unit (46) mounted on the track, and

the transport unit comprises a pivoting (66) mechanism to pivot (P) the picked-up wafer from the horizontal position to the vertical position and back to the horizontal position.

13. (new) The apparatus of claim 12, wherein,

the transport system comprise two of said track, each track being a linear track (24, 26) arranged parallel to the first and second process unit arrays, and

one said transport unit (44, 46) is movably mounted on each said linear track,

said transport unit comprises two wafer holding devices arranged parallel in a back-to-back configuration, each wafer holding device configured to hold one wafer in a vertical plane while moving the held wafer along the linear track, and

a transport path of the held wafer is narrower than a diameter of the held wafer.

14. (new) The apparatus of claim 13, wherein,

each holding device comprises a gripper which contacts the held wafer only on edges of the held wafer.

15. (new) The apparatus of claim 13, wherein,

the transport system further comprises a transfer station (20, 22) located intermediate the cassette-holding unit and the transport unit,

the transfer station arranged to pick the one wafer from the cassette and transfer the one wafer to the transport unit.

16. (new) Apparatus (1) for treating wafer-shaped articles, comprising:

two linearly arranged process unit arrays, the two arrays being parallel to each other and each being comprised of at least two process units that horizontally treat only one single wafer-shaped article (Wm) at one time;

a cassette-holding unit (15) holding a cassette storing one wafer therein; and

a transport system comprising a track located between the two arrays, the transport system configured to

i) pick up the one wafer from the cassette and move the one wafer into a vertical position,

ii) with the one wafer in the vertical position, transport the one wafer along the track to one of the process units, and

iii) move the one wafer from the vertical position into a horizontal position, placing the one wafer in the one process unit for being treated by the one process unit, wherein,

a width of a transport path of the one wafer along the track being less than a width of the wafer-shaped article.

17. (new) The apparatus of claim 16, wherein,

the transport system comprises a transport unit (46) movably mounted on the track,

the transport unit comprising a pivoting (66) mechanism for pivoting (P) the one wafer, i) at the cassette-holding unit, from the horizontal position to the vertical position and ii) at the one process unit, from the vertical position back to the horizontal position.